

#14/C
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[10191/1616] Hayes



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Heribert WEBER et al
Serial No. : 09/699,704
Filed : October 30, 2000
For : MASS FLOW SENSOR HAVING AN IMPROVED
MEMBRANE STABILITY
Art Unit : 2855
Examiner : Martir, Lilybett

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Commissioner for Patents
Washington, D.C. 20231

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AMENDMENT

SIR:

This paper addresses the Final Office Action dated December 2, 2002.
Applicants respectfully request reconsideration in view of the amendments and remarks
below.

IN THE CLAIMS:

Without prejudice, please cancel claim 2 and please amend claims 1, 3, and 8-
12 as follows.

1. (Once Amended) A mass flow sensor, comprising:

- a frame formed at least in part by silicon;
- a membrane held by the frame;
- a metal layer including a first structure and a second structure and being
arranged above the frame;
- a heating element formed by the first structure in the metal layer;

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